

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :
HIROSHI SHINRIKI, ET AL. : EXAMINER: EL ARINI, Z.
SERIAL NO: 10/519,401 : DATE ALLOWED: FEBRUARY 21, 2008
FILED: JANUARY 4, 2005 : GROUP ART UNIT: 1746
FOR: METHOD OF CLEANING :
SUBSTRATE-PROCESSING DEVICE
AND SUBSTRATE-PROCESSING
DEVICE

COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

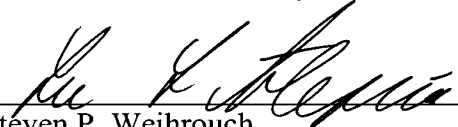
SIR:

The Examiner's Statement of Reasons for Allowance included at page 2 of the Notice of Allowability mailed February 21, 2008, characterizes the claimed inventions in terms of "a method of cleaning a processing apparatus..."

However, Applicants respectfully note that independent Claim 49 recites an apparatus, not a method. Accordingly, Applicants understand the Examiner's Statement of Reasons for Allowance to apply to independent Claims 1 the claims depending therefrom, but not to independent Claim 49 and the claims depending therefrom.

Respectfully submitted,

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